



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/234,233
Filing Date January 20, 1999
Inventor Weimin Li, et al
Assignee Micron Technology, Inc.
Group Art Unit 2818
Examiner D. Vu
Attorney's Docket No. MI22-1035
Title: Semiconductor Processing Methods

INFORMATION DISCLOSURE STATEMENT

References – See Attached Form PTO-1449

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

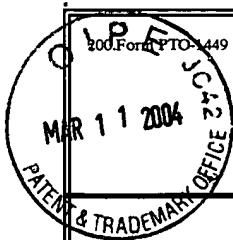
This Supplemental Information Disclosure Statement is being filed together with the filing of the Request for Continued Examination (RCE) Application and prior to the receipt of the first Office Action. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. §1.17(p) to Deposit Account No. 23-0925. Please credit Deposit Account No. 23-0925 with any overpayment of the above fee.

Citation of these references is respectfully requested.

Respectfully submitted,

Dated: 11 May 2004

By: James E. Lake
James E. Lake
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U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
M122-1035SERIAL NO.
09/234,233LIST OF ART CITED BY APPLICANT
(Use several sheets if necessary)APPLICANT
Weimin LiFILING DATE
January 20, 1999GROUP
2818

U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	5,498,555	03/96	Lin			
	AB	6,153,504	11-00	Shields et al.			
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM	7201716	08/95	Japan			x	
	AN	8046186	02/96	Japan			x	
	AO	10-163083	06/98	Japan				

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AP		Wolf, S., Silicon Process., Vol. 2 48-49 and 435				
	AQ						
	AR						

EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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